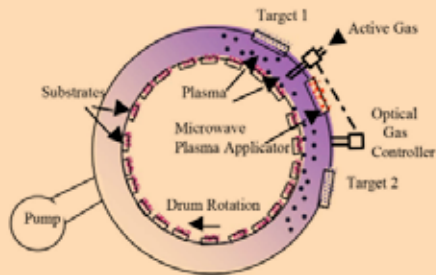


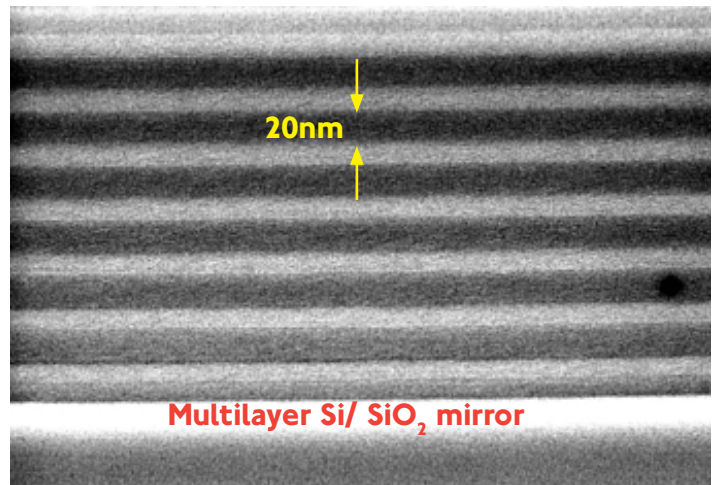
Active Research and Consultancy in

PULSED DC MICROWAVE ACTIVATED PLASMA ASSISTED MAGNETRON SPUTTERING

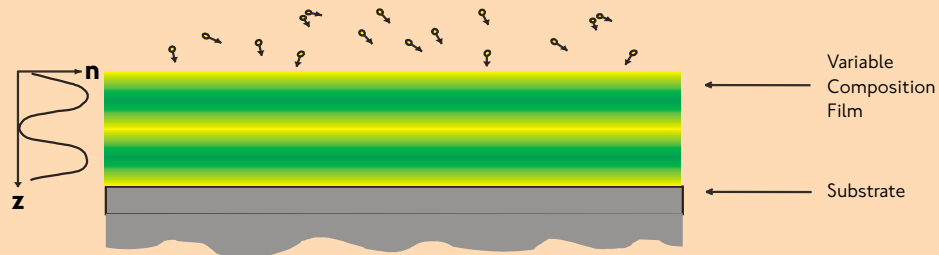
Pulsed DC magnetron microwave plasma magnetron sputtering system. Drum based system, accommodating up to sixteen 4" diameter wafers, achieving $\pm 1\%$ thickness uniformity. Deposits metals, oxides, nitrides, carbides, transparent conductive oxides.



Technique produces high density, stable, adherent coatings at room temperatures.



Graded index coatings possible using pulsed DC microwave plasma sputtering, illustrated as follows:



CONTACT US

Professor Des Gibson
Director, Institute of Thin Films, Sensors & Imaging
University of the West of Scotland
Paisley PA1 2BE, United Kingdom
Tel: 44 (0) 141 848 3610
Email: des.gibson@uws.ac.uk

Lorraine Dymond
Enterprise & Employer Engagement
University of the West of Scotland
Paisley PA1 2BE, United Kingdom
Tel: 44 (0) 141 848 3918
Email: lorraine.dymond@uws.ac.uk

UWS UNIVERSITY OF THE
WEST of SCOTLAND

Institute of Thin Films,
Sensors and Imaging